L Number	Hits	Search Text	DB	Time stamp
1	717	(216/2).CCLS.	USPAT; US-PGPUB	2003/09/24 12:51
2	60	((216/2).CCLS.) and (etch$3 and trench$2).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:37
3	46	((216/2).CCLS.) and ((etch$3 adj stop$3) or (etch-stop)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:07
4	812	(438/22).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:13
5	149	(438/24).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:14
6	453	(438/48).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:14
7	289	(438/50).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:15
8	327	(438/52).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:15
9	738	(438/689).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:16
11	3465	(438/694).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:16
12	374	(438/696).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:16
13	794	(438/702).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:16
14	661	(438/700).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:18
15	484	(438/719).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:18

16	360	(438/734).CCLS.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:19
17	584	(216/24).CCLS.	USPAT; US-PGPUB	2003/09/24 13:34
18	56	((216/24).CCLS.) and etch$3 and trench$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:34
19	69	((216/2).CCLS.) and (trench$2).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:40
20	19	((216/2).CCLS.) and (backside).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:37
22	83	((216/2).CCLS.) and (channel$1).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:42
23	53	((216/2).CCLS.) and (groove$1).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:42
25	1896	(conduct$3 and insulat$3 and silicon and etch$3 and (trench$2 or groove$1 or channel$1)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:47
27	912	((conduct$3 and insulat$3 and silicon and etch$3 and (trench$2 or groove$1 or channel$1)).clm.) and sidewall$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:49
28	100	((conduct$3 and insulat$3 and silicon and etch$3 and (trench$2 or groove$1 or channel$1)).clm.) and backside	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/09/24 13:49
29	11	etch$3 and trench and microstructure$1	JPO; DERWENT	2003/09/24 13:58
30	16	etch$3 and trench and micromechanical	JPO; DERWENT	2003/09/24 13:58
31	1	1999-444471.NRAN.	DERWENT	2003/09/24 14:01
–	319	"electrically isolated electrode"	USPAT; US-PGPUB	2002/08/21 08:19
–	2	(("6256430") or ("6360036")).PN.	USPAT; US-PGPUB	2002/08/22 09:02
–	423	(etch$3 near3 backside) and conduct$3 and insulat$3	USPAT; US-PGPUB	2002/08/22 09:22
–	51	(etch$3 near3 backside) and conduct$3 and insulat$3 and trench and sidewall	USPAT; US-PGPUB	2002/08/22 10:33
–	101	(etch$3 near3 backside) and conduct$3 and insulat$3 and (trench or channel or groove or via or hole) and sidewall	USPAT; US-PGPUB	2002/08/26 14:59
–	377	(etch$3 near3 backside) and conduct$3 and insulat$3 and (trench or channel or groove or via or hole)	USPAT; US-PGPUB	2002/08/23 10:56
–	197	MEMS and etch$3 and SOI	USPAT; US-PGPUB	2003/09/24 13:12
–	743	MEMS and etch$3 and conduct$3 and insulat$3 and(trench or groove or via or hole or channel)	USPAT; US-PGPUB	2002/08/26 14:57

-	3709	isolated near3 (electrode or conduct$3) and etch$3	USPAT; US-PGPUB	2002/08/23 12:33
-	475	(216/18).CCLS.	USPAT; US-PGPUB	2003/09/24 12:51
-	62	(216/19).CCLS.	USPAT; US-PGPUB	2002/08/23 12:34
-	454	(216/24).CCLS.	USPAT; US-PGPUB	2003/09/24 13:33
-	229	(216/39).CCLS.	USPAT; US-PGPUB	2002/08/23 12:37
-	71	(216/46).CCLS.	USPAT; US-PGPUB	2002/08/23 12:40
-	555	(216/79).CCLS.	USPAT; US-PGPUB	2002/08/23 12:40
-	628	(216/99).CCLS.	USPAT; US-PGPUB	2002/08/23 12:41
-	775	MEMS and etch$3 and conduct$3 and insulat$3 and(trench or cavity or groove or via or hole or channel)	USPAT; US-PGPUB	2002/08/23 14:51
-	1	("5980762").PN.	USPAT; US-PGPUB	2002/08/26 09:46
-	8	(silicon adj "110")same trench and etch	USPAT; US-PGPUB	2002/08/26 09:53
-	6229	etch$3 and conduct$3 and insulat$3 and (trench or channel or groove or via or hole or cavity)	JPO; DERWENT	2002/08/26 15:08
-	1	etch$3 and conduct$3 and insulat$3 and (trench or channel or groove or via or hole or cavity)and MEMS	JPO; DERWENT	2002/08/26 15:03
-	598	etch$3 and conduct$3 and insulat$3 and trench	JPO; DERWENT	2002/08/27 10:43
-	12	etch$3 and trench and (microelectromechanical or MEMS)	JPO; DERWENT	2003/09/24 13:57
-	1	("6121552").PN.	USPAT; US-PGPUB	2002/08/27 10:52
-	3	(("6416831") or ("5017947") or ("4233109")).PN.	USPAT; US-PGPUB	2003/04/29 16:49

Inventor Name Search Result

Your Search was:

Last Name = DANEMAN
First Name = MICHAEL

Application#	Patent#	Status	Date Filed	Title	Inventor Name
60357160	Not Issued	159	02/12/2002	FAST MEMS OPTICAL SWITCH ACTUATION USING PRE-BIAS FORCE AND ROTATING MAGNETIC FIELD	DANEMAN, MICHAEL J
60303755	Not Issued	159	07/07/2001	COMPACT MAGNET ASSEMBLY FOR MEMS DEVICE	DANEMAN, MICHAEL J
60250237	Not Issued	159	11/29/2000	MEMS PACKAGE WITH OPTICAL WINDOWS	DANEMAN, MICHAEL J
60250081	Not Issued	159	11/29/2000	SINGLE-WAFER PROCESS TO BUILD MEMS ROTATING MIRRORS WITH PRECISION CLAMPING MECHANISM	DANEMAN, MICHAEL J
60196055	Not Issued	159	04/10/2000	CAPACITIVE SENSING SCHEME FOR MIRROR POSITION DETECTION IN OPTICAL SWITCHES	DANEMAN, MICHAEL J
60192144	Not Issued	159	03/24/2000	METHOD FOR CONTROLLED RELEASE USING ETCH-STOP TRENCHES	DANEMAN, MICHAEL J
60191987	Not Issued	159	03/24/2000	TWO-DIMENSIONAL GIMBALED SCANNING ACTUATOR WITH VERTICAL ELECTROSTATIC COMB-DRIVE FOR ACTUATION AND/OR SENSING	DANEMAN, MICHAEL
10469516	Not Issued	019	01/01/0001	OPTICATL CROSS-CONNECT SYSTEM	DANEMAN, MICHAEL
10003054	Not Issued	120	12/06/2001	HIGH CONTRAST GRATING LIGHT VALVE	DANEMAN, MICHAEL J
09989905	Not Issued	041	11/20/2001	ENCLOSURE FOR MEMS APPARATUS AND METHOD OF USING THE SAME	DANEMAN, MICHAEL J
09949210	Not Issued	041	09/07/2001	TILING OF OPTICAL MEMS DEVICES	DANEMAN, MICHAEL J
09932433	Not Issued	041	08/18/2001	USE OF APPLIED FORCE TO IMPROVE MEMS SWITCH PERFORMANCE	DANEMAN, MICHAEL J
09917490	6480319	150	07/28/2001	APPARATUS AND METHOD FOR 2-	DANEMAN, MICHAEL J

				DIMENSIONAL STEERED-BEAM NXM OPTICAL SWITCH USING SINGLE-AXIS MIRROR ARRAYS	
09917431	6437902	150	07/28/2001	OPTICAL BEAM STEERING SWITCHING SYSTEM	DANEMAN, MICHAEL J
09912150	Not Issued	093	07/23/2001	MECHANICAL LANDING PAD FORMED ON THE UNDERSIDE OF A MEMS DEVICE	DANEMAN, MICHAEL J
09900841	6514781	150	07/07/2001	MAINTAINING THE STATE OF A MEMS DEVICE IN THE EVENT OF A POWER FAILURE	DANEMAN, MICHAEL J
09835115	Not Issued	071	04/13/2001	PROCESS FOR CREATING AN ELECTRICALLY ISOLATED ELECTRODE ON A SIDEWALL OF A CAVITY IN A BASE	DANEMAN, MICHAEL J
09834744	Not Issued	071	04/12/2001	MEMS MIRRORS WITH PRECISION CLAMPING MECHANISM	DANEMAN, MICHAEL J
09812066	Not Issued	071	03/17/2001	THREE DIMENSIONAL OPTICAL SWITCHES AND BEAM STEERING MODULES	DANEMAN, MICHAEL J
09802619	Not Issued	071	03/08/2001	HIGH CONTRAST GRATING LIGHT VALVE	DANEMAN, MICHAEL J
09798129	6528887	150	03/01/2001	CONDUCTIVE EQUIPOTENTIAL LANDING PADS FORMED ON THE UNDERSIDE OF A MEMS DEVICE	DANEMAN, MICHAEL J
09751660	Not Issued	071	12/28/2000	TWO-DIMENSIONAL GIMBALED SCANNING ACTUATOR WITH VERTICAL ELECTROSTATIC COMB-DRIVE FOR ACTUATION AND/OR SENSING	DANEMAN, MICHAEL J
09724948	Not Issued	041	11/28/2000	CAPACITIVE SENSING SCHEME FOR DIGITAL CONTROL STATE DETECTION IN OPTICAL SWITCHES	DANEMAN, MICHAEL J
09712420	Not Issued	041	11/13/2000	FABRICATION AND CONTROLLED RELEASE OF STRUCTURES USING ETCH-STOP TRENCHES	DANEMAN, MICHAEL J
09546432	6586841	150	04/10/2000	MECHANICAL LANDING PAD FORMED ON THE UNDERSIDE OF A MEMS DEVICE	DANEMAN, MICHAEL
09536164	6330102	150	03/25/2000	APPARATUS AND METHOD FOR 2-DIMENSIONAL STEERED-BEAM NXM OPTICAL SWITCH USING SINGLE-AXIS MIRROR ARRAYS AND RELAY OPTICS	DANEMAN, MICHAEL J
09518754	6473544	150	03/03/2000	OPTICAL SWITCH HAVING EQUALIZED BEAM SPREADING IN ALL CONNECTIONS	DANEMAN, MICHAEL
09518751	6449407	150	03/03/2000	OPTICAL SWITCHING HAVING	DANEMAN, MICHAEL

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DANEMAN	MICHAEL	Search

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Inventor Name Search Result

Your Search was:

Last Name = LIN
First Name = CHUANG-CHIA

Application#	Patent#	Status	Date Filed	Title	Inventor Name
10193804	Not Issued	094	07/11/2002	MICROMECHANICAL AND MICROOPTOMECHANICAL STRUCTURES WITH SINGLE CRYSTAL SILICON EXPOSURE STEP	LIN, CHUANG-CHIA
10192087	Not Issued	040	07/09/2002	MICROMECHANICAL AND MICROOPTOMECHANICAL STRUCTURES WITH BACKSIDE METALIZATION	LIN, CHUANG-CHIA
10040687	Not Issued	041	01/07/2002	SELF-ALIGNED MICRO HINGES	LIN, CHUANG-CHIA
09915232	Not Issued	030	07/24/2001	MEMS ELEMENT HAVING PERPENDICULAR PORTION FORMED FROM SUBSTRATE	LIN, CHUANG-CHIA
09915217	6583031	150	07/25/2001	METHOD OF MAKING A MEMS ELEMENT HAVING PERPENDICULAR PORTION FORMED FROM SUBSTRATE	LIN, CHUANG-CHIA
09891760	Not Issued	041	06/25/2001	SELF ASSEMBLED MICRO ANTI-STICTION STRUCTURE	LIN, CHUANG-CHIA
09858469	6413793	150	05/17/2001	METHOD OF FORMING PROTRUSIONS ON SINGLE CRYSTAL SILICON STRUCTURES BUILT ON SILICON-ON-INSULATOR WAFERS	LIN, CHUANG-CHIA
09835115	Not Issued	071	04/13/2001	PROCESS FOR CREATING AN ELECTRICALLY ISOLATED ELECTRODE ON A SIDEWALL OF A CAVITY IN A BASE	LIN, CHUANG-CHIA
09834744	Not Issued	071	04/12/2001	MEMS MIRRORS WITH PRECISION CLAMPING MECHANISM	LIN, CHUANG-CHIA
09724515	6506620	150	11/27/2000	PROCESS FOR MANUFACTURING MICROMECHANICAL AND MICROOPTOMECHANICAL STRUCTURES WITH BACKSIDE METALIZATION	LIN, CHUANG-CHIA
09724514	6479315	150	11/27/2000	PROCESS FOR MANUFACTURING MICROMECHANICAL AND MICROOPTOMECHANICAL	LIN, CHUANG-CHIA

				STRUCTURES WITH SINGLE CRYSTAL SILICON EXPOSURE STEP	
09724506	6479311	150	11/27/2000	PROCESS FOR MANUFACTURING MICROMECHANICAL AND MICROOPTOMECHANICAL STRUCTURES WITH PRE-APPLIED PATTERNING	LIN, CHUANG-CHIA
09718017	Not Issued	071	11/20/2000	SILICON ON INSULATOR AND POLYSILICON WAFER FABRICATION PROCESS FOR MEMS	LIN, CHUANG-CHIA

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LIN	CHUANG-CHIA	Search

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Inventor Name Search Result

Your Search was:

Last Name = KOBRIN
First Name = BORIS

Application#	Patent#	Status	Date Filed	Title	Inventor Name
60485082	Not Issued	020	07/07/2003	APPARATUS & PROCESS FOR VAPOR PHASE DEPOSITION	KOBRIN, BORIS
60479883	Not Issued	020	06/20/2003	DRY PROCESSING TOOL FOR STICTION-FREE MEMS RELEASE	KOBRIN, BORIS
60470971	Not Issued	020	05/16/2003	METHOD OF CONTROLLED OXIDE ETCH	KOBRIN, BORIS
60454700	Not Issued	020	03/17/2003	PROCESS ACTUATION OF MEMS MOVABLE STRUCTURES	KOBRIN, BORIS
60454543	Not Issued	020	03/17/2003	METHOD OF SURFACE MODIFICATION FOR MENS RELEASE AND PASSIVATION	KOBRIN, BORIS
60318099	Not Issued	159	09/07/2001	MEMS OPTICAL SWITCH WITH MOVABLE DIFFRACTION GRATINGS	KOBRIN, BORIS
60255734	Not Issued	159	12/14/2000	MEMS OPTICAL SWITCH WITH PNEUMATIC ACTUATION	KOBRIN, BORIS
60255733	Not Issued	159	12/14/2000	MEMS OPTICAL SWITCH WITH ACOUSTIC PULSE ACTUATION	KOBRIN, BORIS
60250081	Not Issued	159	11/29/2000	SINGLE-WAFER PROCESS TO BUILD MEMS ROTATING MIRRORS WITH PRECISION CLAMPING MECHANISM	KOBRIN, BORIS
60162197	Not Issued	159	10/29/1999	MAGNETIC POLE FABRICATION PROCESS AND DEVICE	KOBRIN , BORIS
60153074	Not Issued	159	09/10/1999	MAGNETIC POLE FABRICATION PROCESS AND DEVICE	KOBRIN , BORIS
60061860	Not Issued	159	10/15/1997	LINEAR, ROTATIONAL AND CONFORNAL ENCODERS, BASED ON FIBER GRATINGS, FOR RELATIVE OR ABSOLUTE MOVEMENT DETECTION, AND METHODS FOR FABRICATION THE SAME	KOBRIN , BORIS
09992531	Not Issued	041	11/06/2001	MEMS OPTICAL SWITCH WITH PNEUMATIC ACTUATION	KOBRIN, BORIS
09992530	Not Issued	041	11/06/2001	MEMS OPTICAL SWITCH WITH ACOUSTIC PULSE ACTUATION	KOBRIN, BORIS

09835115	Not Issued	071	04/13/2001	PROCESS FOR CREATING AN ELECTRICALLY ISOLATED ELECTRODE ON A SIDEWALL OF A CAVITY IN A BASE	KOBRIN, BORIS
09834744	Not Issued	071	04/12/2001	MEMS MIRRORS WITH PRECISION CLAMPING MECHANISM	KOBRIN, BORIS
09789250	Not Issued	161	02/20/2001	TWO-SIDED MEMS DEVICE AND OPTICAL SWITCH	KOBRIN, BORIS
09696739	6547975	150	10/26/2000	MAGNETIC POLE FABRICATION PROCESS AND DEVICE	KOBRIN, BORIS
09658023	6540928	150	09/08/2000	MAGNETIC POLE FABRICATION PROCESS AND DEVICE	KOBRIN, BORIS
09081286	6087655	150	05/19/1998	FIBER GRATING ENCODERS AND METHODS FOR FABRICATING THE SAME	KOBRIN , BORIS

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